## **PATENT**

## IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Applicant: Paul B. Mirkarimi et al.

Docket No.

: CIL-10972

Serial No. : 10/086,614

Art Unit

: 1762

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: March 1, 2002

Examiner

: B. Pianalto

For

: Ion-Assisted Deposition Techniques For

The Planarization Of Topological Defects

## APPLICATION FOR CHANGE IN CORRESPONDENCE ADDRESS

**Commissioner for Patents** P.O. Box 1450 Alexandria, VA 22313-1450

Dear Sir:

Please change the Correspondence Address for the above-identified

application to:

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If you have any questions, please contact the undersigned at 808-270-1011.

Respectfully submitted,

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Dated: September 30, 2004